

#17

00862.022183 (862.C2183)

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	:	Examiner: I. Soward
HARUHITO ONO, ET AL.)	
	:	Group Art Unit: 2822
Appln. No.: 09/819,737)	
	:	
Filed: March 29, 2001)	April 17, 2003
	:	
For: ELECTROOPTIC SYSTEM ARRAY,)	
CHARGED-PARTICLE BEAM	:	
EXPOSURE APPARATUS USING)	
THE SAME, AND DEVICE	:	
MANUFACTURING METHOD)	

RECEIVED

APR 17 2003

Commissioner for Patents
Washington, D.C. 20231

OFFICE OF PETITIONS

SECOND INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed documents are also enclosed.

REMARKS

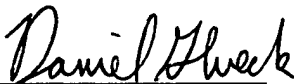
The cited patents were cited in one or more of the cited applications.

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



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